

**WEST****Freeform Search**

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Term:

12 and microelectromechanical

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USPT	15 and microelectromechanical	0	L9
USPT	14 and microelectromechanical	3	L8
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JPAB,EPAB,DWPI	photoresist and (etch\$ or pattern) and oxide and mask\$ and (micromechanical)	0	L6
JPAB,EPAB,DWPI	photoresist and (etch\$ or pattern) and oxide and mask\$ (((438/723  438/734  438/736  438/743  438/753  438/756  438/942 )!.CCLS.)) and photoresist and etch\$ and oxide and mask\$	3019	L5
USPT	((438/723  438/734  438/736  438/743  438/753  438/756  438/942 )!.CCLS.))	528	L4
USPT	((438/723  438/734  438/736  438/743  438/753  438/756  438/942 )!.CCLS.))	1279	L3
USPT	((216/41  216/47  216/79  216/80  216/97  216/99 )!.CCLS.)) and photoresist and etch\$ and oxide and mask\$	475	L2
USPT	((216/41  216/47  216/79  216/80  216/97  216/99 )!.CCLS.))	2323	L1